

# Guofang Zhong

## List of Publications by Year in descending order

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49  
papers

2,023  
citations

279798

23  
h-index

233421

45  
g-index

49  
all docs

49  
docs citations

49  
times ranked

2174  
citing authors

| #  | ARTICLE  | IF   | CITATIONS |
|----|--|------|-----------|
| 1  | Roll-to-roll graphene films for non-disposable electrocardiogram electrodes. Journal Physics D: Applied Physics, 2021, 54, 364003.   | 2.8  | 8         |
| 2  | Low temperature growth of fully covered single-layer graphene using a CoCu catalyst. Nanoscale, 2017, 9, 14467-14475.  | 5.6  | 11        |
| 3  | Metal-catalyst-free growth of graphene on insulating substrates by ammonia-assisted microwave plasma-enhanced chemical vapor deposition. RSC Advances, 2017, 7, 33185-33193.                         | 3.6  | 34        |
| 4  | Growth of continuous graphene by open roll-to-roll chemical vapor deposition. Applied Physics Letters, 2016, 109, .  | 3.3  | 36        |
| 5  | Nondestructive optical visualisation of graphene domains and boundaries. Nanoscale, 2016, 8, 16427-16434.  | 5.6  | 5         |
| 6  | Growth of Continuous Monolayer Graphene with Millimeter-sized Domains Using Industrially Safe Conditions. Scientific Reports, 2016, 6, 21152.  | 3.3  | 48        |
| 7  | Growth of high quality, high density single-walled carbon nanotube forests on copper foils. Carbon, 2016, 98, 624-632.   | 10.3 | 31        |
| 8  | Growth of high-density carbon nanotube forests on conductive TiSiN supports. Applied Physics Letters, 2015, 106, 083108.   | 3.3  | 26        |
| 9  | Influence of Packing Density and Surface Roughness of Vertically-Aligned Carbon Nanotubes on Adhesive Properties of Gecko-Inspired Mimetics. ACS Applied Materials & Interfaces, 2015, 7, 3626-3632. | 8.0  | 33        |
| 10 | Increased carbon nanotube area density after catalyst generation from cobalt disilicide using a cyclic reactive ion etching approach. Journal of Applied Physics, 2014, 115, 144302.                 | 2.5  | 3         |
| 11 | Carbon nanotube forests growth using catalysts from atomic layer deposition. Journal of Applied Physics, 2014, 115, 144303.  | 2.5  | 10        |
| 12 | Single-step CVD growth of high-density carbon nanotube forests on metallic Ti coatings through catalyst engineering. Carbon, 2014, 67, 680-687.  | 10.3 | 22        |
| 13 | High density carbon nanotube growth using a plasma pretreated catalyst. Carbon, 2013, 53, 339-345.   | 10.3 | 24        |
| 14 | Carbon nanotube growth for through silicon via application. Nanotechnology, 2013, 24, 125603.  | 2.6  | 39        |
| 15 | Synthesis of carbon nanotubes and graphene for VLSI interconnects. Microelectronic Engineering, 2013, 107, 210-218.  | 2.4  | 15        |
| 16 | Diameter and wall number control of carbon nanotubes by chemical vapor deposition. Journal of Applied Physics, 2013, 114, .  | 2.5  | 6         |
| 17 | Chemical vapor deposition of carbon nanotube forests. Physica Status Solidi (B): Basic Research, 2012, 249, 2315-2322.   | 1.5  | 22        |
| 18 | Applications of Carbon Nanotubes Grown by Chemical Vapor Deposition. Japanese Journal of Applied Physics, 2012, 51, 01AH01.  | 1.5  | 25        |

| #  | ARTICLE   | IF   | CITATIONS |
|----|---|------|-----------|
| 19 | Growth of Ultrahigh Density Single-Walled Carbon Nanotube Forests by Improved Catalyst Design. ACS Nano, 2012, 6, 2893-2903.  | 14.6 | 184       |
| 20 | Complementary metal-oxide-semiconductor-compatible and self-aligned catalyst formation for carbon nanotube synthesis and interconnect fabrication. Journal of Applied Physics, 2012, 111, . | 2.5  | 13        |
| 21 | Dielectric screening effects on transition energies in aligned carbon nanotubes. Physical Review B, 2012, 85, .   | 3.2  | 17        |
| 22 | Applications of Carbon Nanotubes Grown by Chemical Vapor Deposition. Japanese Journal of Applied Physics, 2012, 51, 01AH01.   | 1.5  | 23        |
| 23 | The mechanism of the sudden termination of carbon nanotube supergrowth. Carbon, 2011, 49, 214-221.  | 10.3 | 16        |
| 24 | High-density growth of horizontally aligned carbon nanotubes for interconnects. Physica Status Solidi (B): Basic Research, 2010, 247, 2669-2672.  | 1.5  | 22        |
| 25 | Observation of excitonic effects in metallic single-walled carbon nanotubes. Physical Review B, 2010, 82, .   | 3.2  | 20        |
| 26 | Post-CMOS wafer level growth of carbon nanotubes for low-cost microsensors—a proof of concept. Nanotechnology, 2010, 21, 485301.  | 2.6  | 27        |
| 27 | Acetylene: A Key Growth Precursor for Single-Walled Carbon Nanotube Forests. Journal of Physical Chemistry C, 2009, 113, 17321-17325.   | 3.1  | 120       |
| 28 | Diffusion- and Reaction-Limited Growth of Carbon Nanotube Forests. ACS Nano, 2009, 3, 3560-3566.  | 14.6 | 127       |
| 29 | Investigating the Diameter-Dependent Stability of Single-Walled Carbon Nanotubes. ACS Nano, 2009, 3, 1557-1563.   | 14.6 | 82        |
| 30 | Use of carbon nanotubes for VLSI interconnects. Diamond and Related Materials, 2009, 18, 957-962.   | 3.9  | 54        |
| 31 | Carbon nanotubes for interconnects in VLSI integrated circuits. Physica Status Solidi (B): Basic Research, 2008, 245, 2303-2307.  | 1.5  | 11        |
| 32 | Controlling the Catalyst During Carbon Nanotube Growth. Journal of Nanoscience and Nanotechnology, 2008, 8, 6105-6111.  | 0.9  | 12        |
| 33 | Growth Kinetics of 0.5 cm Vertically Aligned Single-Walled Carbon Nanotubes. Journal of Physical Chemistry B, 2007, 111, 1907-1910.   | 2.6  | 165       |
| 34 | Semi-quantitative study on the fabrication of densely packed and vertically aligned single-walled carbon nanotubes. Carbon, 2006, 44, 2009-2014.  | 10.3 | 84        |
| 35 | Very High Yield Growth of Vertically Aligned Single-Walled Carbon Nanotubes by Point-Arc Microwave Plasma CVD. Chemical Vapor Deposition, 2005, 11, 127-130.                                | 1.3  | 85        |
| 36 | Low Temperature Synthesis of Extremely Dense and Vertically Aligned Single-Walled Carbon Nanotubes. Japanese Journal of Applied Physics, 2005, 44, 1558-1561.                               | 1.5  | 130       |

| #  | ARTICLE  | IF  | CITATIONS |
|----|--|-----|-----------|
| 37 | Direct Evidence for Root Growth of Vertically Aligned Single-Walled Carbon Nanotubes by Microwave Plasma Chemical Vapor Deposition. <i>Journal of Physical Chemistry B</i> , 2005, 109, 19556-19559. | 2.6 | 68        |
| 38 | Large-Area Synthesis of Carbon Nanofibers by Low-Power Microwave Plasma-Assisted CVD. <i>Chemical Vapor Deposition</i> , 2004, 10, 125-128.  | 1.8 | 21        |
| 39 | Synthesis of highly oriented and dense conical carbon nanofibers by a DC bias-enhanced microwave plasma CVD method. <i>Thin Solid Films</i> , 2004, 464-465, 315-318.                                | 1.8 | 12        |
| 40 | Selective growth of carbon nanostructures on nickel implanted nanopyramid array. <i>Applied Surface Science</i> , 2004, 234, 72-77.  | 6.1 | 9         |
| 41 | Multi-walled carbon nanotube-based gas sensors for NH <sub>3</sub> detection. <i>Diamond and Related Materials</i> , 2004, 13, 1327-1332.  | 3.9 | 136       |
| 42 | Memory effects of carbon nanotube-based field effect transistors. <i>Diamond and Related Materials</i> , 2004, 13, 1967-1970.  | 3.9 | 18        |
| 43 | CVD diamond: a novel high $\hat{\beta}$ -coating for plasma display panels?. <i>Diamond and Related Materials</i> , 2001, 10, 809-817.   | 3.9 | 50        |
| 44 | Deposition of large area high quality diamond wafers with high growth rate by DC arc plasma jet. <i>Diamond and Related Materials</i> , 2000, 9, 1673-1677.  | 3.9 | 8         |
| 45 | Economical deposition of a large area of high quality diamond film by a high power DC arc plasma jet operating in a gas recycling mode. <i>Diamond and Related Materials</i> , 2000, 9, 1655-1659.   | 3.9 | 37        |
| 46 | Carbon transition efficiency and process cost in high-rate, large-area deposition of diamond films by DC arc plasma jet. <i>Diamond and Related Materials</i> , 2000, 9, 1682-1686.                  | 3.9 | 9         |
| 47 | Input power dependence of growth rate and quality of diamond films deposited in a d.c. arcjet system. <i>Diamond and Related Materials</i> , 1999, 8, 211-214.                                       | 3.9 | 9         |
| 48 | Fracture behavior of thick diamond films prepared by DC arc plasma jet method. <i>Diamond and Related Materials</i> , 1998, 7, 733-736.  | 3.9 | 12        |
| 49 | A new type of DC arc plasma torch for low cost large area diamond deposition. <i>Diamond and Related Materials</i> , 1998, 7, 737-741.   | 3.9 | 44        |